

※ This announcement is for foreigners who have difficulty using Korean.

As a government-funded research institution, Korea Research Institute of Standards and Science(KRISS) performs research involving basic and original technology in all areas of science and technology. Based on the National Competency Standards associated with blind recruitment, it now calls for competent scientists from various areas who are encouraged to pursue their dream and passion at KRISS.

## ☐ Areas for Employment

Field		Assigned Task	Personnel	Code
Physical Metrology	Length and Dimensional Metrology	<ul style="list-style-type: none"> <li>• Remote imaging using computational imaging</li> <li>• Development of adaptive optical closed loop algorithm</li> </ul>	1	A01
	Acoustics, Ultrasound and Vibration Metrology	<ul style="list-style-type: none"> <li>• Development of optics-based underwater ultrasonic measurement standards</li> <li>• Advancement of acoustic lens technology</li> <li>• Research and development of evaluation technology for medical ultrasound</li> </ul>	1	A02
Chemical and Material Metrology	Material Property Metrology1	<ul style="list-style-type: none"> <li>• Development of a tuning-fork-based vacuum PiFM system and a liquid-phase PiFM platform for nanoscale spatially resolved spectroscopic characterization of nanobiomaterials</li> </ul>	1	B01
	Material Property Metrology2	<ul style="list-style-type: none"> <li>• Development of measurement platforms for quantum materials and their device applications using scanning probe microscopes</li> </ul>	1	B02
Biomedical Metrology	Biometrology1	<ul style="list-style-type: none"> <li>• Development of measurement standards for advanced biopharmaceuticals and biomaterials for precision medicine</li> <li>• Development of reference materials and measurement methods for quality control of advanced biopharmaceuticals</li> </ul>	1	C01
	Biometrology2	<ul style="list-style-type: none"> <li>• Measurements of lipid nanoparticles and virus</li> <li>• Measurements of RNA</li> </ul>	1	C02
	Biometrology3	<ul style="list-style-type: none"> <li>• Prokaryotic genome/metagenome analysis</li> <li>• Virus genome/virome analysis</li> <li>• LLM-based literature analysis and agent developments</li> </ul>	1	C03

Field		Assigned Task	Personnel	Code
	Nanobio Measurement1	<ul style="list-style-type: none"> <li>• Development of optical imaging technologies based on interferometry (Digital Holography) for biomedical applications</li> <li>• Development of nanobio materials and cell analysis for ATMP using hyperspectral dark-field microscopy</li> </ul>	1	C04
	Nanobio Measurement2	<ul style="list-style-type: none"> <li>• Development of optical imaging technologies based on interferometry(optical coherence tomography) or nonlinear optics for biomedical applications</li> <li>• Development of optoretinography technology and preclinical evaluation technology for gene therapy efficacy using this technology</li> </ul>	1	C05
	Nanobio Measurement3	<ul style="list-style-type: none"> <li>• Efficacy and toxicity evaluation of advanced biopharmaceuticals and nanomaterials using proteomics</li> <li>• Protein corona characterization and mechanism elucidation</li> <li>• Development of quantitative LC - MS/MS methodologies and multi-omics data analysis</li> </ul>	1	C06
Quantum Technology	Quantum Magnetic Sensing1	<ul style="list-style-type: none"> <li>• Development of a Magneto-Optical Kerr Effect Microscope</li> <li>• Application Experiments Using Magneto-Optical Kerr Effect Microscope</li> </ul>	1	D01
	Quantum Magnetic Sensing2	<ul style="list-style-type: none"> <li>• Development of skyrmion motion technology using photon squeezing</li> <li>• Development of fundamental technologies for implementing quantum skyrmions</li> <li>• Analysis of the characteristics of skyrmion-based probabilistic devices</li> </ul>	2	D02
	Quantum Magnetic Sensing3	<ul style="list-style-type: none"> <li>• Development of metrology application based on quantum magnetic sensors such as optically-pumped atomic magnetometers(OPM)</li> <li>• Development of minute magnetic field imaging and non-invasive electric current distribution density reconstruction methods</li> </ul>	1	D03
	Quantum Information Networking	<ul style="list-style-type: none"> <li>• Quantum optical sensing technology and metrology</li> <li>• Quantum entangled photon pair sources and quantum interferometry technology</li> </ul>	1	D04
	Quantum Device	<ul style="list-style-type: none"> <li>• Research and development of hybrid quantum systems based on superconducting microwave quantum circuits</li> </ul>	1	D05
	Atomic Quantum Sensing1	<ul style="list-style-type: none"> <li>• Research on the Control of Laser-Cooled Atoms</li> <li>• Research on Gravity, gravity gradiometer and Inertial Sensors Using Atomic Interferometers</li> </ul>	2	D06

Field		Assigned Task	Personnel	Code
	Atomic Quantum Sensing2	<ul style="list-style-type: none"> <li>• Generation and control of on-chip microcombs</li> <li>• Development of quantum information systems based on atomic chipcells and photonic integrated circuits</li> </ul>	1	D07
	Atomic Quantum Sensing3	<ul style="list-style-type: none"> <li>• Measurement and control technologies for neutral-atom quantum computer development</li> <li>• Development of quantum computing and logic gate technologies using neutral-atom qubits</li> <li>• Development of technologies for the practical operation and system management of quantum computers</li> </ul>	2	D08
Strategic Technology Research	Semiconductor and Display Metrology1	<ul style="list-style-type: none"> <li>• Improvement of optical module for metrology/inspection instrument based on extreme ultraviolet (EUV) light source</li> <li>• Performance evaluation of optical properties for EUV materials such as pellicles and photoresist</li> <li>• Development of EUV-based surface profilometer for advanced semiconductor devices</li> </ul>	1	E01
	Semiconductor and Display Metrology2	<ul style="list-style-type: none"> <li>• Development and Performance Evaluation of Battery Materials and Devices based on Raman spectroscopy</li> </ul>	1	E02
	Semiconductor and Display Metrology3	<ul style="list-style-type: none"> <li>• Development of real-time monitoring technology for key reactive species in semiconductor etching processes using laser spectroscopy and its application to carbon-neutrality processes</li> </ul>	1	E03
	Semiconductor and Display Metrology4	<ul style="list-style-type: none"> <li>• Study on the atmospheric chemical dynamics of alternative GHGs for semiconductor processes using comb-based time- and frequency-resolved spectroscopy</li> </ul>	1	E04
	Space Metrology	<ul style="list-style-type: none"> <li>• Optical metrology for space optics</li> <li>• Development of automatic polishing technology for large mirror</li> <li>• Development of large mirror using SiC</li> </ul>	1	E05
	Emerging Research Instruments	<ul style="list-style-type: none"> <li>• R&amp;D for enhancing and quantifying AI reliability (Uncertainty in AI, Trustworthy AI, etc.)</li> <li>• AI R&amp;D for solving challenges in advanced industries</li> </ul>	1	E06
Superconducting Quantum Computing System1		<ul style="list-style-type: none"> <li>• Design and optimization of high-performance superconducting quantum processor architecture for error correction</li> <li>• Optimization of qubit frequency allocation based on unit cells</li> <li>• High fidelity quantum gate simulation</li> <li>• Design of variable couplers for fast quantum gates</li> <li>• Development of Purcell filters for high measurement fidelity</li> </ul>	1	F01

Field	Assigned Task	Personnel	Code
Superconducting Quantum Computing System <sup>2</sup>	<ul style="list-style-type: none"> <li>• Superconducting qubit control and noise analysis for quantum gate implementation</li> <li>• Development of ultra-low noise measurement technologies for high measurement fidelity</li> <li>• Development of integrated software for operating large-scale QPUs (100 qubits or more)</li> <li>• Development and experimental application of error correction and error mitigation methodologies</li> </ul>	1	F02
Superconducting Quantum Computing System <sup>3</sup>	<ul style="list-style-type: none"> <li>• Development of high-performance superconducting QPU fabrication processes</li> <li>• 3D packaging for QPUs with 100 qubits or more</li> <li>• Yield and variance control of large-area wafer-scale QPUs</li> <li>• Quality control of large-area superconducting thin films, wafer-scale electron-beam lithography processes, and optimization of Josephson junction processes</li> </ul>	1	F03
Meta-Touch	<ul style="list-style-type: none"> <li>• Development of ultra-compact and ultra-lightweight actuator technology capable of reproducing ultra-realistic tactile sensations</li> </ul>	1	F04

※ Candidates can apply in only one of the recruitment fields, and admission is cancelled if overlapping or cross-applications are confirmed.

## ☐ Eligibility

Classifi- cation	Description
Post-doc.	<ul style="list-style-type: none"><li>○ Eligibility requirements<ul style="list-style-type: none"><li>– Those who do not fall under the reasons for disqualification for appointment<ul style="list-style-type: none"><li>• Those who have not suspended or deprived voting rights by law</li><li>• Those who have not evaded military service obligations</li><li>• Those who have not been caught for fraudulent employment</li><li>• Those who have not been dismissed due to misconduct</li><li>• Those without reasons for disqualification for overseas travel</li></ul></li><li>– Those who earned their Ph.D. within the past 5 years or will earn their Ph.D. within the next 3 months as of the scheduled date of employment</li></ul></li><li>○ Preferential treatment<ul style="list-style-type: none"><li>– Those of national merit, those eligible for employment support, those with disabilities and Women in science and technology are eligible for preferential treatment if they submit evidentiary documents.</li></ul></li></ul>

## ☐ How to apply

- Online application on the KRISS job page (<https://kriss.fairy.im/>)
- Period for submission: December 29th, 2025 (Monday) - January 13th, 2026 (Tuesday), 11:00 AM
- ※ Korean time(UTC+9)

## □ Process

Process	Description
1st screening (Document)	<ul style="list-style-type: none"> <li>○ Evaluation of expertise and competence in each area for employment               <ul style="list-style-type: none"> <li>– Evaluation items: performance, experience, capability, competence, etc.</li> <li>– Criteria for passing: Each applicant will be evaluated with a five-point scale in comprehensive consideration of evaluation items. Applicants who earn high scores among those who earn at least 80 points on average based on the aggregate points granted by each evaluator.</li> <li>– No. of applicants selected: within three times the expected number of new hires</li> </ul> </li> </ul>
2nd screening (Interview)	<ul style="list-style-type: none"> <li>○ Research performance seminar and personality interview               <ul style="list-style-type: none"> <li>– Evaluation items: basic attitude, thinking ability, presentation ability, potential, knowledge</li> <li>– Criteria for passing: Applicants who earn high scores among those who earn at least 80 points on average based on the aggregate points granted by each evaluator.</li> <li>– No. of applicants selected: within the expected number of new hires</li> </ul> </li> </ul>

※ Applicants who reside overseas may have a video interview in the 2nd screening.

## □ Required documents

Classification	Description
Application form	<ul style="list-style-type: none"> <li>○ Self-introduction, experience statement, article and patent performance list, etc.</li> <li>※ Fill out through the online job posting website.</li> </ul>
Before 2nd screening	<ul style="list-style-type: none"> <li>○ Presentation materials for research performance seminar</li> <li>○ Certificates of graduation of all university/graduate school programs               <ul style="list-style-type: none"> <li>※ Only official certificates of graduation(official diplomas) are acceptable. Provisional certificates(letter, etc.) are not accepted.</li> <li>※ Documents submitted before 2<sup>nd</sup> screening are not provided to evaluators.</li> </ul> </li> </ul>
After 2nd screening	<ul style="list-style-type: none"> <li>○ Transcripts of graduation of all university/graduate school programs</li> <li>○ Proof of research achievements(paper, patent, etc.) written in application form</li> <li>○ Proof of career/employment, copies of certificates of qualifications, certificate of military service (if applicable)</li> <li>○ Certificate of disability, certificate of eligibility for employment protection (if applicable)</li> <li>※ Documents submitted after 2<sup>nd</sup> screening are not provided to evaluators.</li> </ul>

## ☐ Timeline

Process	Date	Remarks
Employment notice	From December 29th, 2025 to January 13th, 2026	Timeline is subject to change due to the institution's circumstances.
Receipt of application forms	From December 29th, 2025 to January 13th, 2026	
1st screening	Mid-January, 2026	
2nd screening	End of January, 2026 to early February, 2026	
Announcement of successful applicants of 2nd screening	Mid-February, 2026	
Scheduled date of employment	March 1, 2026	

## ☐ Training conditions

Classification	Description
Term of contract	<ul style="list-style-type: none"><li>○ Contract within one year<ul style="list-style-type: none"><li>※ Training is possible until the end of the project in the 5th year after obtaining doctoral degree.</li><li>※ If the result of training evaluation is insufficient, the training period cannot exceed 3 years.</li></ul></li></ul>
Working conditions	<ul style="list-style-type: none"><li>○ Wage: To be determined through career grading applicable to regular employees based on the institution's own evaluation criteria</li></ul>

## □ Other information

- Failure to comply with the blind recruitment requirements during screening process may result in penalties such as deductions.

- Do not write prejudice factors—such as age, gender, place of origin, family relations, and the applicant's name—in the self-introduction letter. (You can fill out prejudice factors if requested directly on the application form though.)

- Candidates will be selected within the planned number of successful candidates for each stage. If no qualified candidates are identified in a given field, the position may remain unfilled.
- Candidates are responsible for any disadvantages resulting from omitted documents or false entries/submissions.
- If any fraudulent behavior or false information is discovered during the screening process, acceptance and appointment may be canceled.
- Candidates found to have engaged in fraudulent practices may be restricted from applying for public institution recruitment exams for the next five years.
- Reserve candidates may be selected in preparation for possible cancellations or declinations of final offers.
- In accordance with Article 11 of the Fair Hiring Procedure Act, applicants may request the return of original submitted documents after the hiring decision has been finalized. Documents will be returned upon identity verification.
- Preferential treatment will be given to eligible persons such as veterans and persons with disabilities in accordance with relevant laws, provided that supporting documents are submitted.
- To enhance institutional competitiveness and attract talent with job competency, KRISS may collect and use information such as the name of the university/graduate school attended, research laboratory, and academic advisor.
- For further inquiries, please contact the recruitment website's Q&A section.
  - Email: [ssbaek@kriss.re.kr](mailto:ssbaek@kriss.re.kr)